

AF/1763 *AFW*



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:  
Ling Chen, et al.

Serial No.: 10/032,284

Confirmation No.: 4034

Filed: December 21, 2001

For: Gas Delivery Apparatus  
And Method For Atomic  
Layer Deposition

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§ Group Art Unit: 1763  
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§ Examiner: Moore, Karla A  
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MAIL STOP AF  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

CERTIFICATE OF MAILING	
37 C.F.R. § 1.8	
I hereby certify that this correspondence is being deposited on July 14, 2004 with the United States Postal Service as First Class Mail in an envelope addressed to: Mail Stop AF, Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450.	
7/14/04	<i>[Signature]</i>
Date	Signature

Dear Sir:

**RESPONSE TO FINAL OFFICE ACTION DATED APRIL 23, 2004**

In response to the Final Office Action dated April 23, 2004, having a shortened statutory period for response set to expire on July 23, 2004, please enter this response and reconsider the claims pending in the application for reasons discussed below. Although Applicants believe that no additional fees are due in connection with this response, the Commissioner is hereby authorized to charge counsel's Deposit Account No. 20-0782/AMAT/5192.02/KMT, for any fees, including extension of time fees or excess claim fees, required to make this response timely and acceptable to the Office.

**Amendments to the Specification** begin on page 2 of this paper. **Amendments to the Claims** begin on page 17 of this paper. **Amendments to the Drawings** begin on page 30 of this paper. **Remarks** begin on page 31 of this paper.